



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Fischer et al.

Examiner: Wilson, Lee

Application No. 10/077,072

Art Unit: 2821

Filed: February 14, 2002

Docket No. P0877

For: Plasma Processing Apparatus and  
Method for Confining an RF Plasma  
Under Very High Gas Flow and  
RF Power Density Conditions

Date: February 14, 2002

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on February 12, 2003.

Signed: Sharon D. Tillery  
Sharon D. Tillery

REQUEST TO RESCIND PREVIOUS NONPUBLICATION REQUEST

Commissioner for Patents  
Washington, DC 20231

Sir:

I hereby **rescind** the previous request that the above-identified application not be published under 35 U.S.C. § 122(b)(2)(B)(ii).

Respectfully submitted,  
Lam Research Corporation

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